

10:20-11:20, November 16, 2021



Study on Silicon Sphere  
Polishing for New SI  
Standards

Prof. Chao-Chang A. Chen, Ph.D.

University Distinguish Professor,  
ME/NTUST, Taiwan  
Director, CMP Innovation  
Center, NTUST, Taiwan  
Deputy General Director, Center  
for Measurement Standards,  
Industrial Technology Research  
Institute, Taiwan

Prof. Chao-Chang A. Chen obtained his M.S. I.E. and Ph.D. M.E. degrees from University of Wisconsin, Madison, USA in 1991 and 1994, respectively. Professor Chen establishes the CMP Innovation Center (CIC) in National Taiwan University of Science and Technology (NTUST) and also works as the Director of CIC. He was also appointed as a Visiting Researcher at Manufacturing Technology Center, TSMC during March to July, 2015. At present he serves as Deputy General Director in Center for Measurement Standards, Industrial Technology Research Institute (ITRI).

Prof. Chen's research interests include the areas of wafer and film processing with CMP, precision molding of optical elements with micro structures, and manufacturing analysis. Prof. Chen has received over 20 patents and invited as a guest editor of the Journal of Materials Processing Technology (Sep. 2003) and co-editor of the Advances in Abrasive Technology XIII, Advanced Materials Research (Sep. 2010). He also received SME President Award in 2015 and SEMI Taiwan Merit Award in 2013 and SEMI Taiwan Standard Contribution Award in 2016.

Prof. Chen serves as a board member of various academic/professional associations, including the CMP User Group, Taiwan (CMPUG\_Taiwan), the Taiwan Society of Abrasive Technology (TSAT) and the Taipei Chapter of the Society of Manufacturing Engineers (SME).